

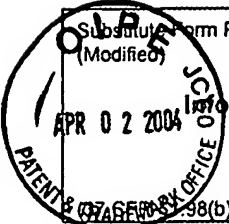
Substitute Form PTO-1449 (Modified) APR 02 2004 U.S. DEPT. OF COMMERCE PATENT & TRADEMARK OFFICE (37 CFR 1.98(b))	U.S. Department of Commerce Patent and Trademark Office		Attorney's Docket No. 09712-341001	Application No.
	<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary)			
	Applicant Peter de Groot et al.		Filing Date March 8, 2004	Group Art Unit

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
MAL	AA	4,576,479	03/18/1986	Downs	356	351	
↑	AB	4,999,014	03/12/1991	Gold et al.	356	382	
↓	AC	5,133,601	07/28/1992	Cohen et al.	356	359	
	AD	5,602,643	02/11/1997	Barrett	356	360	
	AE	6,545,763	04/08/2003	Kim et al.	356	503	
MAL	AF	6,597,460	07/22/2003	Groot et al.	356	512	
	AG						
	AH						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
MAL	AI	0 397 388 A2	11/14/1990	EPO	G01B	11/06		
MAL	AJ	0 549 166 A2	06/30/1993	EPO	G01B	11/06		
	AK							
	AL							

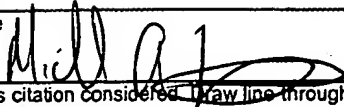
Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
MAL	AM	Dresel, Thomas et al., "Three-dimensional sensing of rough surfaces by coherence radar", <u>Applied Optics</u> , Vol. 31, No. 7, pp. 919-925 (March 1, 1992)
↑	AN	Feke, Gilbert D. et al., "Interferometric back focal plane microellipsometry", <u>Applied Optics</u> , Vol. 37, No. 10, pp. 1796-1802 (April 1, 1998)
↓	AO	Kim, Seung-Woo et al., "Thickness-profile measurement of transparent thin-film layers by white-light scanning interferometry", <u>Applied Optics</u> , Vol. 38, No. 28, pp. 5968-5973 (October 1, 1999)
	AP	Kino, Gordon S. et al., "Mirau correlation microscope", <u>Applied Optics</u> , Vol. 29, No. 26, pp. 3775-3783 (September 10, 1990)
	AQ	Pelligrand, S. et al., "Mesures 3D de topographies et de vibrations a l'échelle (sub)micrométrique par microscopie optique interférométrique", <u>Proc. Club CMOI, Methodes et Techniques Optiques pour l'Industrie</u> (2002)
↓	AR	Pluta, Maksymilian, "Advanced Light Microscopy", Vol. 3, (Elsevier, Amsterdam, 1993) pp. 265-271
MAL	AS	Rosencwaig, Allan et al., "Beam profile reflectometry: A new technique for dielectric film measurements", <u>Applied Physics Letters</u> , Vol. 60, No. 11, pp. 1301-1303 (March 16, 1992)

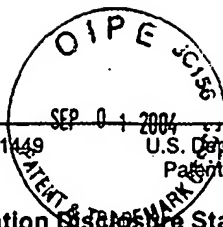
Examiner Signature <i>Mill R</i>	Date Considered 2-15-2006
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

	Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 09712-341001	Application No.
	<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary)		Applicant Peter de Groot et al.	
			Filing Date March 8, 2004	Group Art Unit
	(7) 35 U.S.C. 112(b)			

**Other Documents (include Author, Title, Date, and Place of Publication)**

Examiner Initial	Desig. ID	Document
MA L	BA	Sandoz, Patrick "Wavelet transform as a processing tool in white-light interferometry", <u>Optics Letters</u> , Vol. 22, No. 14, pp. 1065-1067 (July 15, 1997)
MA L	BB	Shatalin, S.V. et al., "Reflection conoscopy and micro-ellipsometry of isotropic thin film structures", <u>Journal of Microscopy</u> , Vol. 179, Part 3, pp. 241-252 (September, 1995)
	BC	
	BD	

Examiner Signature 	Date Considered 7-15-2006
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Sheet 1 of 1

Substitute Form PTO-1449 (Modified)  <b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary)  (37 CFR §1.98(b))	Attorney's Docket No. <b>09712-341001</b>	Application No. <b>10/795,808</b>
	Applicant <b>Peter de Groot et al.</b>	
	Filing Date <b>March 8, 2004</b>	Group Art Unit <b>2877</b>

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
<i>ML</i>	AA	5,398,113	03/14/1995	de Groot	356	360	
<i>ML</i>	AB	5,587,792	12/24/1996	Nishizawa et al.	355	356	
<i>ML</i>	AC	5,900,633	05/04/1999	Solomon et al.	250	339.08	
<i>ML</i>	AD	6,242,739	06/05/2001	Cherkassky	250	339.11	
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
<i>ML</i>	AL	0 929 094 A2	07/14/1999	EPO	H01L	21/00		
	AM							
	AN							
	AO							
	AP							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	AQ	
	AR	
	AS	
	AT	

Examiner Signature <i>M. de Groot</i>	Date Considered <b>2-15-2006</b>
EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Substitute Disclosure Form (PTO-1449)

Substitute Form PTO-1449

U.S. Department of Commerce  
Patent and Trademark OfficeAttorney's Docket No.  
09712-341001Application No.  
10/795,808**Information Disclosure Statement  
by Applicant**

(Use several sheets if necessary)

Applicant  
Peter de Groot et al.Filing Date  
March 8, 2004Group Art Unit  
2877

(37 CFR 1.102(b))

**U.S. Patent Documents**

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
MAC	AA	5,129,724	7/14/1992	Brophy et al.	356	357	
	AB						
	AC						
	AD						

**Foreign Patent Documents or Published Foreign Patent Applications**

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
MAC	AE	0 617 255 A1	09/28/1994	EPO	G01B	11/06		
MAC	AF	WO 02/082008	10/17/2002	WIPO	G01B	9/02		
	AG							
	AH							
	AI							

**Other Documents (include Author, Title, Date, and Place of Publication)**

Examiner Initial	Desig. ID	Document
	AJ	
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	AM	

Examiner Signature

Date Considered

7-15-2006

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